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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI et al.
Title: METHOD OF CLEANING SUBSTRATE PROCESSING
APPARATUS
Appl. No.: 10/555,668
Filing Date: 12/21/2005
Examiner: Nicole R. Blan
Art Unit: 1792
Confirmation No.: 9889

AMENDMENT AND REPLY UNDER 37 C.F.R. 1.111

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated November 16, 2007, concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 5 of this document.

Please amend the application as follows: